



PTO/SB/08A (08-03)

Substitute for Form 1449A/PTO INFORMATION DISCLOSURE STATEMENT BY APPLICANT (use as many sheets as necessary)			Complete if Known		
			Application Number	10/808,774	
			Filing Date	March 24, 2004	
			First Named Inventor	Oeda, Takahashi	
			Art Unit	2162	
			Examiner Name	Jean M. Corielus	
Sheet	1	of	2	Attorney Docket Number	16869P-009910US

U.S. PATENT DOCUMENTS+					
Examiner Initials*	Cite No. ¹	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number Kind Code ² (if known)			
<i>[initials]</i>	1	6,509,828	01-21-2003	Bolavage et al.	
<i>[initials]</i>	2	2002/0029224	03-07-2002	Carlsson	
<i>[initials]</i>	3	6,167,405	12-26-2000	Rosensteel et al.	
<i>[initials]</i>	4	6,122,630	09-19-2000	Strickler et al.	
<i>[initials]</i>	5	5,884,028	03-16-1999	Kindell et al.	
<i>[initials]</i>	6	5,831,985	11-03-1998	Sandorfi et al.	
<i>[initials]</i>	7	5,849,168	07-15-1997	Huang et al.	
<i>[initials]</i>	8	5,830,087	05-13-1997	Kindell et al.	
<i>[initials]</i>	9	5,479,656	12-26-1995	Rawlings, III	
<i>[initials]</i>	10	5,457,793	10-10-1995	Elko et al.	
<i>[initials]</i>	11	5,006,978	04-09-1991	Neches	
<i>[initials]</i>	12	4,585,516	04-29-1986	Corn et al.	
<i>[initials]</i>	13	4,464,223	08-07-1984	Gorin.	

FOREIGN PATENT DOCUMENTS								
Examiner Initials*	Cite No. ¹	Foreign Patent Document			Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ⁶
		Country Code ³	Number ⁴	Kind Code ⁵ (if known)				
	14	PCT	WO99/54805	A	10-28-1999	Sun Microsystems		<input type="checkbox"/>
	15	EP	0869436	A	10-07-1998	Hitachi, Ltd.		<input type="checkbox"/>
	16	PCT	WO98/35291	A	08-13-1998	New Frame Corp.		<input type="checkbox"/>
	17	PCT	WO97/35269	A	09-25-1997	EMC Corp.		<input type="checkbox"/>

Examiner Signature	<i>Jean M. Corielus</i>	Date Considered	6-19-05
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. ¹ Applicant's unique citation designation number (optional). ² Kind Codes of U.S. Patent Documents at www.uspto.gov or MPEP 901.04. ³ Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). ⁴ For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. ⁵ Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. ⁶ Applicant is to place a check mark here if English language Translation is attached.

Substitute for form 1449B/PTO				Complete if Known	
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Sheet	2	of	2	Attorney Docket Number	16869P-009910US

NON PATENT LITERATURE DOCUMENTS			
Examiner Initials *	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
<i>JA</i>	18	"SAN Basics: A Technical White Paper from MetaStor Storage Solutions," LSI Logic Corporation Milpitas, CA (September 1999).	
<i>JA</i>	19	"Tegal says TEL enjoined from selling etchers with dual-frequency technology," Semiconductor Business News, http://seminews.com/sbn/sbnh2/news/19990901a1.shtml (September 1999).	
<i>JA</i>	20	SINGER "The Challenge: Automating the Industry," Technical Program Proceedings Semicon / West 1984 San Mateo, California pp. 272-275 (May 1984).	
<i>JA</i>	21	ZAJAC et al. "Automated Plasma Etch Systems for VLSI," Technical Program Proceedings Semicon / West 1984 San Mateo, California pp 27-35. (May 1984).	
<i>JA</i>	22	ZAJAC et al. "Multi-Electrode Plasma Etching," Tegal Process Review, pp. 1-3, Tegal Corp. Petaluma, CA (May 1984).	

Examiner Signature	<i>Jean M. Corrielus</i>	Date Considered	6-19-05
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